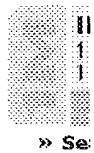


	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments	Error Definition	Errors
1	BRS	L1	2	5238354.pn. 5870488.pn.	USPAT	2004/09/24 12:43			0
2	BRS	L2	87736 5	(wafer semiconductor (semi adj conductor) substrate)	USPAT; US-PGPUB	2004/09/24 13:01			0
3	BRS	L3	37140	mark\$ near (identif\$ locat\$ verif\$ read scan\$)	USPAT; US-PGPUB	2004/09/24 13:05			0
4	BRS	L4	2248	2 same 3	USPAT; US-PGPUB	2004/09/24 13:09			0
5	BRS	L5	17043 5	2 same (rotat\$ turn\$)	USPAT; US-PGPUB	2004/09/24 13:09			0
6	BRS	L6	243	5 same 3	USPAT; US-PGPUB	2004/09/24 13:40			0
7	BRS	L7	38	6 same (ccd camera scanner (scanning adj device) detecttor (photo adj detector) photodetector)	USPAT; US-PGPUB	2004/09/24 13:47			0
8	BRS	L8	13175	(calculat\$ correct\$) near (motion rotat\$)	USPAT; US-PGPUB	2004/09/24 13:47			0
9	BRS	L9	34	6 and 8	USPAT; US-PGPUB	2004/09/24 13:47			0
10	BRS	L10	24	9 and (ccd camera scanner (scanning adj device) detecttor (photo adj detector) photodetector)	USPAT; US-PGPUB	2004/09/24 13:47			0

IEEE HOME | SEARCH IEEE | SHOP | WEB ACCOUNT | CONTACT IEEE


[Membership](#) [Publications/Services](#) [Standards](#) [Conferences](#) [Careers/Jobs](#)
IEEE Xplore
RELEASE 1.5

 Welcome
 United States Patent and Trademark Office

[Help](#) [FAQ](#) [Terms](#) [IEEE Peer Review](#)
[Quick Links](#)

» Search

Welcome to IEEE Xplore

- ☐ Home
- ☐ What Can I Access?
- ☐ Log-out

Tables of Contents

- ☐ Journals & Magazines
- ☐ Conference Proceedings
- ☐ Standards

Search

- ☐ By Author
- ☐ Basic
- ☐ Advanced

Member Services

- ☐ Join IEEE
- ☐ Establish IEEE Web Account
- ☐ Access the IEEE Member Digital Library

IEEE Enterprise

- ☐ Access the IEEE Enterprise File Cabinet

Print Format

 Your search matched **9** of **1074479** documents.

 A maximum of **500** results are displayed, **15** to a page, sorted by **Relevance Descending** order.

Refine This Search:

You may refine your search by editing the current search expression or enter new one in the text box.

☐ Check to search within this result set

Results Key:
JNL = Journal or Magazine **CNF** = Conference **STD** = Standard

1 Magnetic combinatorial thin-film libraries
Russek, S.E.; Bailey, W.E.; Alers, G.; Abraham, D.L.;

Magnetics, IEEE Transactions on , Volume: 37 , Issue: 4 , July 2001

Pages:2156 - 2158

[\[Abstract\]](#)
[\[PDF Full-Text \(91 KB\)\]](#)
IEEE JNL
2 New microcharacters for wafer identification
Suzuki, E.; Matsuda, H.; Chiba, T.; Mori, A.;

Semiconductor Manufacturing, IEEE Transactions on , Volume: 14 , Issue: 3 , 2001

Pages:180 - 186

[\[Abstract\]](#)
[\[PDF Full-Text \(172 KB\)\]](#)
IEEE JNL
3 Improvement in reading precision of micro-ID engraved on wafer
Uchida, I.; Suzuki, N.; Arikado, T.; Saitoh, Y.; Fujimoto, K.; Nakajima, K.;

Semiconductor Manufacturing, 2003 IEEE International Symposium on , 30 S Oct. 2003

Pages:43 - 46

[\[Abstract\]](#)
[\[PDF Full-Text \(330 KB\)\]](#)
IEEE CNF
4 New identification system for individual wafer management
Suzuki, E.; Matsuda, H.; Chiba, T.; Mori, A.;

Semiconductor Manufacturing, 2000. Proceedings of ISSM 2000. The Ninth International Symposium on , 26-28 Sept. 2000

Pages:33 - 36

[\[Abstract\]](#)
[\[PDF Full-Text \(434 KB\)\]](#)
IEEE CNF

5 Identification of wafer defect clusters using a self-organizing multil perceptron*Chenn-Jung Huang;*

Neural Information Processing, 2002. ICONIP '02. Proceedings of the 9th International Conference on , Volume: 2 , 18-22 Nov. 2002

Pages:839 - 843 vol.2

[\[Abstract\]](#) [\[PDF Full-Text \(514 KB\)\]](#) [IEEE CNF](#)

6 Application of neural networks and filtered back projection to wafer defect cluster identification*Chenn-Jung Huang;*

Electronic Materials and Packaging, 2002. Proceedings of the 4th International Symposium on , 4-6 Dec. 2002

Pages:99 - 105

[\[Abstract\]](#) [\[PDF Full-Text \(465 KB\)\]](#) [IEEE CNF](#)

7 Multivariate process modeling: the 'preprocessing' challenge*Mastrangelo, C.; Forrest, D.;*

Systems, Man, and Cybernetics, 2001 IEEE International Conference on , Volume: 3 , 7-10 Oct. 2001

Pages:1478 - 1483 vol.3

[\[Abstract\]](#) [\[PDF Full-Text \(408 KB\)\]](#) [IEEE CNF](#)

8 In-fab identification of silicon wafers with clean, laser marked barcode*Fresonke, D.;*

Advanced Semiconductor Manufacturing Conference and Workshop. 1994. AS 94 Proceedings. IEEE/SEMI , 14-16 Nov. 1994

Pages:157 - 160

[\[Abstract\]](#) [\[PDF Full-Text \(544 KB\)\]](#) [IEEE CNF](#)

9 SEM/EDS analysis method for bare silicon particle monitor wafers*Sullivan, N.; Arsenault, S.;*

Advanced Semiconductor Manufacturing Conference and Workshop. 1994. AS 94 Proceedings. IEEE/SEMI , 14-16 Nov. 1994

Pages:293 - 296

[\[Abstract\]](#) [\[PDF Full-Text \(388 KB\)\]](#) [IEEE CNF](#)

[Home](#) | [Log-out](#) | [Journals](#) | [Conference Proceedings](#) | [Standards](#) | [Search by Author](#) | [Basic Search](#) | [Advanced Search](#) | [Join IEEE](#) | [Web Account](#) | [New this week](#) | [OPAC Linking Information](#) | [Your Feedback](#) | [Technical Support](#) | [Email Alerting](#) | [No Robots Please](#) | [Release Notes](#) | [IEEE Online Publications](#) | [Help](#) | [FAQ](#) | [Terms](#) | [Back to Top](#)

Copyright © 2004 IEEE — All rights reserved